IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

Applicants: Davis, et al.

Case: 7938/ETCH/SILICON/JB

Serial No.: 10/628,001

Filed: July 25, 2003

Examiner: Stevenson, Andre C.

Group Art Unit: 2812

Confirmation No.: 3943

Title: METHOD FOR AUTOMATIC DETERMINATION OF SEMICONDUCTOR

PLASMA CHAMBER MATCHING AND SOURCE OF FAULT BY

COMPREHENSIVE PLASMA MONITORING

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

SIR:

AMENDMENT UNDER 37 C.F.R. §1.312

Please enter this amendment and reconsider the claims pending in the application for reasons discussed below. Although the Applicants believe that no fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for any fees, including extension of time fees, and any other fees required to make this response timely and acceptable to the Office.